

## WEST Search History

DATE: Friday, March 21, 2003

<u>Set Name</u>	<u>Query</u>	<u>Hit Count</u>	<u>Set Name</u>
side by side			result set
<i>DB=USPT,PGPB,JPAB,EPAB,DWPI,TDBD; PLUR=YES; OP=ADJ</i>			
L14	L13 and (wafer near inspect\$4)	8	L14
L13	L7 and ((vertical near3 wafer) or (horizontal near2 shaft))	294	L13
L12	L7 and ((semiconductor adj wafer\$2) near3 inspect\$4)	13	L12
L11	L7 AND L3	1	L11
L10	L9 and (mass adj spectrometer)	1	L10
L9	L7 and L1	68	L9
L8	L7 and L4	1	L8
L7	(rotat\$5 near3 shaft) and ((vacuum adj chuck) or (suction adj cup))	2832	L7
L6	L4 and (rotat\$5 near3 shaft)	1	L6
L5	L4 and (wafer\$2 near2 edge)	3	L5
L4	L3 and L1	38	L4
L3	((ICP adj2 MS) or ((inductively adj coupled adj plasma) near2 (mass adj spectrometer)))	548	L3
L2	(analy\$5 near4 solvent) with ((ICP adj2 MS) or ((inductively adj coupled adj plasma) near2 (mass adj spectrometer)))	4	L2
L1	wafer and contaminat\$5 and solvent	6384	L1

END OF SEARCH HISTORY